

Resource Summary Report

Generated by T1D on Aug 1, 2026

Rigaku: Onyx 3000

RRID:SCR_020455

Type: Tool

Proper Citation

Rigaku: Onyx 3000 (RRID:SCR_020455)

Resource Information

URL: <https://www.rigaku.com/products/semi/onyx>

Proper Citation: Rigaku: Onyx 3000 (RRID:SCR_020455)

Description: Hybrid XRF and optical metrology fab tool. Used for thickness, composition, defect identification and sizing of films and structures on blanket and patterned wafers.

Resource Type: instrument resource

Keywords: Rigaku, Semiconductor Metrology, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: Rigaku: Onyx 3000

Resource ID: SCR_020455

Alternate IDs: Model_Number_Onyx

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260801T190647+0000

Ratings and Alerts

No rating or validation information has been found for Rigaku: Onyx 3000.

No alerts have been found for Rigaku: Onyx 3000.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.